

INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Docket: 748-58343		App:	
				Applicant: Austen et al.			
				Filed: Herewith		Art Unit:	
U.S. PATENT DOCUMENTS							
Init.*		Number	Date	Name	Class	Sub	Filed
FOREIGN PATENT DOCUMENTS							
		Number	Date	Country	Class	Sub	
KM		PCT/US00/25002	03/29/01	Schultz et al.			
OTHER DOCUMENTS							
KM			Jones, "Advances in Thermal Profiling for Reflow Process Control," Presented at SMTA 2000 Conference (2000)				
KM			Kazmierowicz, "The Science Behind Conveyor Oven Thermal Profiling," http://www.kicthermal.com/library/tsbcotp.html , (1992)				
KM			"The Process Window Index: A Method For Quantifying Thermal Profile Performance," 3 pages, (date and author unknown)				
KM			KIC Pilot™ Reflow Expert Systems, http://www.kicthermal.com/products/pilot.html , (2000)				
EXAMINER: <i>Karen McHenry</i>				DATE <i>7/24/03</i>			